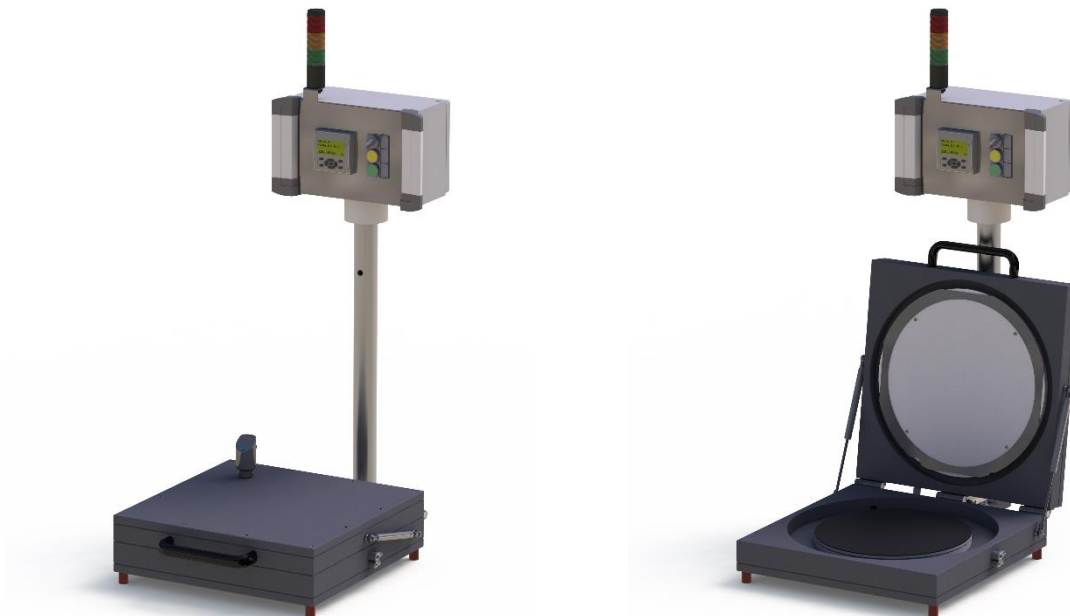


Semi-Automatic Vacuum Wafer Mounter V-200



POWATEC's V-200 Wafer Mounter is a highly specialized semi-automatic device for highest requirements in adhesion results of 200mm wafers or substrates onto a frame mounted film. It is mostly used in advanced research and development departments or series production of large companies. The personnel can achieve a throughput of up to 60 mounts per hour with minimal instruction. The strength of the V-200 lies in:

- the high quality of the reproducibility of the results
- highest requirements for homogeneous and concentric lamination of flat wafers or substrates
- controlled, highly re-producible and minimal force exertion onto the wafer or substrate

Whether silicon wafers or glass, ceramics, FF4, Kapton or other substrates - there are almost no limits to the variety of wafers or substrates to be processed. POWATEC can customize the modular V-200 for your process requirements even for Taiko wafers or wafer bonding.

The extremely short set-up times, low operating costs, slim dimensions and the qualitatively outstanding and reproducible end-results for special applications have made the V-300 a product of great international demand in clean room applications for over a decade.

Product Features

- 60-80 seconds per mount
- Vacuum performance of 1-3 mbar absolute (-1 bar)
- Automatic process consists of vacuum generation and controlled mounting sequence
- Adjustable mounting speed
- Display of mounting vacuum
- Table-top device
- Applicable for clean room application

Unique Selling Proposition

- high quality of the reproducibility of the results
- highest requirements for homogeneous and concentric lamination of flat wafers or substrates
- controlled, highly re-producible and minimal force exertion onto the wafer or substrate
- Minimal maintenance (< 100 USD per year)

Chamber Dimensions & Mechanical Specification

Wafer-size:	up to 200 mm
Frame-size:	8" (OD 276 mm)
Frame Type:	Disco and K&S, Steel Material only
Width:	322 mm
Height:	900 mm
Depth:	522 mm
Weight:	28.4 kg

Electrical Specification

Main power	110-240 VAC, 50/60 Hz
Power supply for control unit	Input 85-240 VAC
	Output 24 VDC/1.5A
	Power max. 25 W

Pneumatic Specification

Required vacuum	3 mbar absolute
Vacuum connection	Festo PUN-8, Ø8 mm
Required air pressure	4-6 bar
Pressure connection	Festo PUN-6, Ø6 mm

Accessory



Vacuum-Pump

0.55KW, 220-240V, 50/60 Hz

Comes with active carbon filter and exhaust particle remover designed from POWATEC for clean room application

Conformity

Build according to IEC 204-1

CE marking

Related Products from POWATEC



Manual Wafer Mounter P-200

Mounting of up to 200mm Wafer onto 8" Film Frame



UV Flash Curing System UF-300

Curing of up to 300mm Wafer onto 300mm Film Frame



Vacuum Wafer Mounter V-200

Mounting of up to 200mm Wafer onto 8" Film Frame



Wafer Frame Magazine

200mm Wafer onto 8" Film Frame, 25 slots